

WAVELINK

WL-250

200mm Semi-Automatic Probe Station

The WaveLink 250 represents the upper limit in computer-controlled analytical wafer probing. Designed to be the flagship of our RF/MW line, it is equally at home at 5 fA as it is at 110 GHz. Whether you simply need EMI or RFI isolation, or frost-free characterization at -55 °C, the WL-250 should be your platform of choice. SIGNATONE, you asked - *We Listened!*



PERFORMANCE, QUALITY, VALUE

SIGNATONE®

Advanced Microprobing Solutions Since 1968

Specifications

Wafer Stage

- ♦ 2000mm wafer chuck and XY stage with 2 independent theta calibration chucks.

X & Y Axis Resolution:	0.1 μ
X & Y Axis Repeatability:	0.5 μ
X & Y Axis Accuracy:	\pm 3 μ
Z Axis Resolution:	0.1 μ
Z Axis Accuracy:	0.25 μ
Theta Range:	\pm 6 $^{\circ}$
- ♦ Programmable Z speed with Soft-Z edge-sense option for probe card applications

Mechanical Features

- ♦ 2" aircraft aluminum base with integrated vibration isolation
- ♦ 0.625" aluminum platen (steel optional) with 1" aluminum channel sub-platen brace
- ♦ Leadscrew-driven platen drive: 0.15" Contact/Separate, 1.75" height adjustment range with lock
- ♦ 2"x2" programmable microscope transport with 10" X 6mm cross-roller bearings, 4" pneumatic Quick-lift
- ♦ Roll-out wafer stage for convenient wafer loading

Motion Control Features

- ♦ Local and Remote operation (RS-232C, GPIB, ActiveX)
- ♦ USB or Ethernet controller to prober communication to eliminate bus conflicts
- ♦ Joystick option with 2-axis joystick and 3-axis optically-encoded thumbwheels for sub- μ control
- ♦ Integrated standard support for up to 4 Computer-Aided Positioners

System Software Features

- ♦ Single level user interface with icons and ToolTips
- ♦ 2-point software theta auto-alignment
- ♦ Programmable Z with *Contact/Separate/Overdrive* presets
- ♦ On-screen live video display with image capture/save
- ♦ Integrated Wafer Map and editor with "*Click to Die*" and "*Row/Column Navigation*"
- Local Step & Repeat debug/diagnostic mode
- ♦ Unlimited Save/Restore of prober setup files and wafer maps
- ♦ Color-coded wafer map with 256 user-defined binning colors
- ♦ Sub-Site probing capability for wafer stage or Computer-Aided Positioners, with editor
- ♦ Learn Mode for saving program probe points
- ♦ Integrated thermal chuck control
- ♦ *Point & Shoot, Drag & Drop, Measure Mode, and Probe/Scope Tracking*
- ♦ Microscope objective compensation
- ♦ Dual inker support (Inkers not included)
- ♦ Supports: LABView, Keithley KITE, Agilent VEE, IC-CAP, ICS Metrics

Supported Applications

- ♦ S-Parameters, 1/f, Load-Pull, Noise Figure, Pulsed RF
- ♦ Low-leakage (<5fA), CV/IV, V_{TH} , T_{OX} , WLR,
- ♦ Lucas Labs Resistivity Measurement Suite

Hardware Options

- ♦ Local enclosure for dry, dark, and EMI/RFI shielded probing
- ♦ Opto-Electronic configurations with optical breadboard drilled platen and/or base
- ♦ Hot-only (to 300 $^{\circ}$ C) and full-range (-55 $^{\circ}$ C to 300 $^{\circ}$ C) **SIGNATONE** thermal chuck systems
- ♦ Temperature-controlled platen and chuck mount for improved thermal settling and safety

SIGNATONE

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